



BOX AF  
RESPONSE UNDER 37 CFR 1.116  
Expedited Handling Procedure  
AU 1763  
PATENT  
2342-111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

APPLICANT: Kazuyuki TOYODA et al.

APPL. NO.: 08/905,971

GROUP: 1763

FILED: August 5, 1997

EXAMINER: R. Zervigon

FOR: SUBSTRATE PROCESSING APPARATUS

#15101  
MW

AMENDMENT UNDER 37 C.F.R. §1.116

Assistant Commissioner for Patents  
Washington, D.C. 20231

June 29, 2001

Sir:

In reply to the Office Action dated January 17, 2001, the period for response having been extended for three (3) months to July 17, 2001, the following remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

34. (Amended) A substrate processing apparatus as recited in claim 1, wherein

the apparatus is configured to transfer a plurality of substrate at a time and to process a plurality of substrate at a time.

Please add the following new claims:

--35. A substrate processing apparatus as recited in claim 1, further including a plurality

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01 FC:103 36.00 OP  
02 FC:117 890.00 OP

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